

Day : Monday Date: 1/12/2004 Time: 09:01:01

Inventor Name Search Result

Your Search was:

Last Name = NAKAMURA First Name = TOSHITAKA

Application#	Patent#	Status	Date Filed	Title	Inventor Name 10
10477596	Not Issued	019	01/01/0001	METHOD FOR TREATING OSTEOCHONDROSIS AND APPARATUS FOR TREATING OSTEOCHONDROSIS	NAKAMURA ET AL, TOSHITAKA
10224598	Not Issued	020	08/21/2002	STRUCTURE FOR PREVENTING GLASS FROM BREAKING AND PLASMA DISPLAY DEVICE	NAKAMURA, TOSHITAKA
10145119	Not Issued	061	05/15/2002	GLASS CRACK PREVENTION FILM-LIKE LAYER AND PLASMA DISPLAY DEVICE	NAKAMURA, TOSHITAKA
09808104	6548177	150	03/15/2001	TRANSPARENT SHOCK- ABSORBING LAMINATE AND FLAT PANEL DISPLAY USING THE SAME	NAKAMURA, TOSHITAKA
09746228	Not Issued	071		TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	NAKAMURA, TOSHITAKA
09729785	<u>6569516</u>	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	NAKAMURA, TOSHITAKA
09608006	6398900	150		METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	NAKAMURA, TOSHITAKA
09458805	6235398			PLASMA DISPLAY PANEL FILTER UTILIZING SAME	NAKAMURA , TOSHITAKA
	6252703			FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	NAKAMURA , TOSHITAKA
<u>09404709</u>	6333592	150	09/24/1999		NAKAMURA , TOSHITAKA

Inventor Search Completed: No Records to Display.

Search Another: Inventor Last Name First Name NAKAMURA TOSHITAKA Search

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Day : Monday Date: 1/12/2004 Time: 08:56:37

Inventor Name Search Result

Your Search was:

Last Name = MIYAUCHI First Name = KAZUHIKO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 10	
10288441	Not Issued	030	11/06/2002	GLASS-BREAK PREVENTING FILM LIKE FILTER AND PLASMA DISPLAY APPARATUS	MIYAUCHI, KAZUHIKO	
10274986	Not Issued	030	10/22/2002	TRANSPARENT PRESSURE- SENSITIVE ADHESIVE COMPOSITION AND PRESSURE- SENSITIVE ADHESIVE SHEET THEREOF	MIYAUCHI, KAZUHIKO	
10224598	Not Issued	020	08/21/2002	STRUCTURE FOR PREVENTING GLASS FROM BREAKING AND PLASMA DISPLAY DEVICE	MIYAUCHI, KAZUHIKO	
10145119	Not Issued	061	05/15/2002	GLASS CRACK PREVENTION FILM-LIKE LAYER AND PLASMA DISPLAY DEVICE	MIYAUCHI, KAZUHIKO	
09808104	6548177			TRANSPARENT SHOCK- ABSORBING LAMINATE AND FLAT PANEL DISPLAY USING THE SAME	MIYAUCHI, KAZUHIKO	
09746228	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	MIYAUCHI, KAZUHIKO	
09729785	6569516	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	MIYAUCHI, KAZUHIKO	
<u>09608006</u>	6398900	150		METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	MIYAUCHI, KAZUHIKO	
	6235398			TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	MIYAUCHI, KAZUHIKO	
<u>09455904</u>	6252703	150			MIYAUCHI, KAZUHIKO	

Inventor Search Completed: No Records to Display.

Search Another: Inventor Last Name

First Name

MIYAUCHI	KAZUHIKO	Search

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Day : Monday Date: 1/12/2004 Time: 08:57:34

Inventor Name Search Result

Your Search was:

Last Name = HIEDA First Name = YOSHIHIRO

Application	# Patent#	Status			Inventor Name 15
10288441	Not Issued	030		2 GLASS-BREAK PREVENTING FILM LIKE FILTER AND PLASMA DISPLAY APPARATUS	HIEDA, YOSHIHIRO
10274986	Not Issued	030		TRANSPARENT PRESSURE- SENSITIVE ADHESIVE COMPOSITION AND PRESSURE- SENSITIVE ADHESIVE SHEET THEREOF	HIEDA, YOSHIHIRO
10224598	Not Issued	020		STRUCTURE FOR PREVENTING GLASS FROM BREAKING AND PLASMA DISPLAY DEVICE	HIEDA, YOSHIHIRO
10145119	Not Issued	061	05/15/2002	GLASS CRACK PREVENTION FILM-LIKE LAYER AND PLASMA DISPLAY DEVICE	HIEDA, YOSHIHIRO
09808104	6548177	150	03/15/2001	TRANSPARENT SHOCK- ABSORBING LAMINATE AND FLAT PANEL DISPLAY USING THE SAME	HIEDA, YOSHIHIRO
<u>09746228</u>	Not Issued	071		TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	HIEDA, YOSHIHIRO
09729785		150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	HIEDA, YOSHIHIRO
		150		METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	HIEDA, YOSHIHIRO
<u>09458805</u>	6235398	150		TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	HIEDA , YOSHIHIRO
	6252703			FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	HIEDA , YOSHIHIRO
			09/28/1997	REVERSIBLE HEAT-SENSITIVE RECORDING MATERIAL	HIEDA , YOSHIHIRO
08281687	5472929	150	07/28/1994	REVERSIBLE HEAT-SENSITIVE RECORDING MEDIUM AND	HIEDA , YOSHIHIRO

			MAGNETIC CARD USING THE SAME	
08240528	5604175	150	REVERSIBLE HEAT-SENSITIVE RECORDING MEDIUM	HIEDA , YOSHIHIRO
07925257	5258350	150	REVERSIBLE HEAT-SENSITIVE RECORDING MATERIAL AND MAGNETIC CARD USING THE SAME	HIEDA , YOSHIHIRO
07732003	5229350	150	REVERSIBLE HEAT-SENITIVE RECORDING MATERIAL AND MAGNETIC CARD USING THE RECORDING MATERIAL	HIEDA , YOSHIHIRO

Inventor Search Completed: No Records to Display.

Search Another: Inventor	Last Name	First Name	
Switch intendiction, inventor	HIEDA	YOSHIHIRO	Search

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Day : Monday Date: 1/12/2004 Time: 08:59:01

Inventor Name Search Result

Your Search was:

Last Name = SASA First Name = KAZUAKI

Application	# Patent#	Status	Date Filed	Title	Inventor Name 51
10471103	Not Issued	020		COMPLEX CATALYST, PROCESS FOR PRODUCING THE COMPLEX CATALYST, AND PROCESS FOR PRODUCING ALCHOHOL DERIVATIVE WITH THE COMPLEX CATALYST	Inventor Name 51 SASAKI, KAZUAKI
10407421	Not Issued	030	04/07/2003	TRANSPARENT CONDUCTIVE LAMINATE AND PROCESS OF PRODUCING THE SAME	SASA, KAZUAKI
10304710	Not Issued	030	11/27/2002	SEMICONDUCTOR LIGHT- EMITTING DEVICE	SASAKI, KAZUAKI
10253609	Not Issued	041	09/25/2002	SEMICONDUCTOR LIGHT- EMITTING DEVICE AND METHOD FOR MANUFACTURING THEREOF	SASAKI, KAZUAKI
<u>10198178</u>	Not Issued	030		MEDICINE, CARRIER FOR MEDICINE, METHOD OF PRODUCING MEDICINE, AND METHOD OF TUMOR TREATMENT	SASAKI, KAZUAKI
10189627	Not Issued	061	07/08/2002	FABRICATION METHOD OF SEMICONDUCTOR LIGHT- EMITTING DEVICE	SASAKI, KAZUAKI
10083575	Not Issued	041	02/27/2002	METHOD FOR PRODUCING OPTICALLY ACTIVE CHRYSANTHEMIC ACID	SASAKI, KAZUAKI
10075284	Not Issued		02/15/2002	THERAPEUTIC ULTRASOUND SYSTEM	SASAKI, KAZUAKI
09839114	6399409	150		METHOD FOR FABRICATING SEMICONDUCTOR LIGHT EMITTING ELEMENT	SASAKI, KAZUAKI
09838592	<u>6476421</u>	150		SEMICONDUCTOR LIGHT- EMITTING DEVICE AND METHOD FOR MANUFACTURING THEREOF	SASAKI, KAZUAKI
09830423	<u>6511428</u>	150	04/26/2001	ULTRASONIC MEDICAL TREATING DEVICE	SASAKI, KAZUAKI
09801844	<u>6572839</u>	150		SENSITIZER FOR TUMOR TREATMENT	SASAKI, KAZUAKI
09757689	6399965	150		SEMICONDUCTOR LIGHT EMITTING DEVICE WITH HIGH YIELD AND LOW POWER CONSUMPTION	SASAKI, KAZUAKI

00746000		70	7	7	
09746228	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	SASA, KAZUAKI
09729785	6569516	5 150		TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	SASA, KAZUAKI
09671777	6465812	150	09/27/2000	SEMICONDUCTOR LIGHT EMITTING DEVICE	SASAKI, KAZUAKI
09608006	6398900	150	06/30/2000	METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	SASA, KAZUAKI
09490534	6468818	150		METHOD FOR PRODUCING A HIGH-LUMINANCE SEMICONDUCTOR LIGHT- EMITTING DEVICE CAPABLE OF OPERATING AT A LOW VOLTAGE	SASAKI, KAZUAKI
09458805	6235398	150	12/10/1999	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	SASA, KAZUAKI
09455904	6252703	150	12/07/1999	TRANSPARENT LAMINATE AND FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	SASA , KAZUAKI
09404709	6333592	150	09/24/1999	FILTER FOR PLASMA DISPLAY PANEL	SASA , KAZUAKI
09238503	6268525	150	01/27/1999	PROCESS FOR PRODUCING OPTICALLY ACTIVE CHRYSANTHEMIC ACID	SASAKI, KAZUAKI
09205184	6074889	150		METHOD FOR PRODUCING SEMICONDUCTOR LIGHT- EMITTING DEVICE WITH UNDOPED SPACER LAYER	SASAKI , KAZUAKI
09015052	6246078	150		SEMICONDUCTOR LIGHT EMITTING ELEMENT	SASAKI, KAZUAKI
08742695	6216538	150		PARTICLE HANDLING APPARATUS FOR HANDLING PARTICLES IN FLUID BY ACOUSTIC RADIATION PRESSURE	SASAKI , KAZUAKI
<u>08668086</u>	5717709	150		SEMICONDUCTOR LIGHT- EMITTING DEVICE CAPABLE OF HAVING GOOD STABILITY IN FUNDAMENTAL MODE OF OSCILLATION, DECREASING CURRENT LEAKAGE, AND LOWERING OSCILLATION ITHESHOLD LIMIT, AND METHOD OF MAKING THE SAME	SASAKI , KAZUAKI
08652357	5856682	150	[]	SEMICONDUCTOR LIGHT- EMITTING DEVICE AND METHOD FOR PRODUCING THE SAME	SASAKI , KAZUAKI

08435391	5516722	150	05/05/199	SEMICONDUCTOR LIGHT- EMITTING DEVICE CAPABLE OF HAVING GOOD STABILITY IN FUNDAMENTAL MODE OF OSCILLATION, DECREASING CURRENT LEAKAGE, AND LOWERING OSCILLATION THRESHOLD LIMIT, AND METHOD OF MAKING THE SAME	SASAKI , KAZUAKI
08409067	Not Issued	161		ALDOL CONDENSATION DEHYDRATION AND CATALYST THEREFOR	SASAKI, KAZUAKI
08314585	5571750	150		METHOD FOR PRODUCING A SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
08270115	5404031	150	07/01/1994	SEMICONDUCTOR LIGHT EMITTING DEVICE WITH CURRENT CONFINING LAYER	SASAKI, KAZUAKI
08253363	Not Issued	166	06/03/1994	SEMICONDUCTOR LIGHT- EMITTING DEVICE CAPABLE OF HAVING GOOD STABILITY IN FUNDAMENTAL MODE OF OSCILLATION, DECREASING CURRENT LEAKAGE, AND LOWERING OSCILLATION THRESHOLD LIMIT, AND METHOD OF MAKING THE SAME	SASAKI , KAZUAKI
08163290	Not Issued	166	12/02/1993	PARTICLE HANDLING APPARATUS FOR HANDLING PARTICLES IN FLUID BY ACOUSTIC RADIATION PRESSURE	SASAKI , KAZUAKI
08148329	Not Issued	161	11/08/1993	ALDOL CONDENSATION DEHYDRATION AND CATALYST THEREFOR	SASAKI , KAZUAKI
<u>08056906</u>	Not Issued	161		MAGNESIUM ALUMINIUM COMPLEX COMPOUNDS, PROCESS FOR PREPARING THE SAME AND PROCESS OF ALDOL CONDENSATION DEHYDRATION PRODUCTS USING THE SAME	SASAKI, KAZUAKI
08025434	Not Issued	166	03/03/1993	OTD WOOD TO SEE	SASAKI , KAZUAKI
07998436	5260231	150	12/30/1992		SASAKI , KAZUAKI
07995064	5413956	150	12/22/1992		SASAKI , KAZUAKI
07980666	5309001	150	11/24/1992	LIGHT-EMITTING DIODE HAVING A SURFACE ELECTRODE OF A TREE-LIKE FORM	SASAKI, KAZUAKI
07883397	<u>5243081</u>	150		ALDOL CONDENSATION DEHYDRATION CATALYST, A PROCESS FOR PREPARING THE SAME AND A PROCESS FOR	SASAKI , KAZUAKI

				PREPARING AN ALDOL CONDENSATION DEHYDRATE USING THE PROCESS	
07879583	5237107	150	05/07/1992	MAGNESIUM. ALUMINIUM COMPLEX COMPOUNDS, PROCESS FOR PREPARING THE SAME AND PROCESS OF ALDOL CONDENSATION DEHYDRATION PRODUCTS USING THE SAME	SASAKI, KAZUAKI
07762769	5228047			SEMICONDUCTOR LASER DEVICE AND A METHOD FOR PRODUCING THE SAME	SASAKI , KAZUAKI
07739767	5171706	150		METHOD FOR THE PRODUCTION OF A SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
07727375	5208468	150	07/05/1991	SEMICONDUCTOR LASER DEVICE WITH A SULFUR-CONTAINING FILM PROVIDED BETWEEN THE FACET AND THE PROTECTIVE FILM	SASAKI, KAZUAKI
07513508	5042044	150	04/27/1990	SEMICONDUCTOR LASER DEVICE, A SEMICONDUCTOR WAFER	SASAKI , KAZUAKI
<u>07474272</u>	Not Issued	166	02/02/1990	SEMICONDUCTOR LASER DEVICE AND A METHOD FOR THE PRODUCTION OF THE SAME	SASAKI , KAZUAKI
07456673	5022036	150	12/27/1989	SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
07406903	4984244	250	09/13/1989	SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
07347099	Not Issued	166	05/03/1989	METHOD FOR THE PRODUCTION OF SEMICONDUCTOR DEVICES	SASAKI , KAZUAKI
07286682	4977568	150	12/19/1988	SEMICONDUCTOR LASER DEVICE	SASAKI, KAZUAKI
<u>06534868</u>	<u>4592623</u>	150	09/22/1983	POLARIZING PLATE	SASA , KAZUAKI

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Search Another: Inventor	Last Name	First Name	
Source Thomas Inventor	SASA	KAZUAKI	Search

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L Number	Hits		DB	Time stamp
1	1	6548177.pn.	USPAT;	2004/01/12 09:09
2	57	(Nolsemune 4-	US-PGPUB	
	5/	(Nakamura.in. or Sasa.in. or Hieda.in. or	USPAT;	2004/01/12 09:16
		Miyauchi.in. or (Nitto adj Denko).as.) and		
		((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag or	EPO; JPO;	1
	İ	(transparent near2 conduct\$3)) with	DERWENT; IBM TDB	
		(temperature))	IDM_IDB	
3	11	(Nakamura.in. or Sasa.in. or Hieda.in. or	USPAT;	2004/01/12 09:17
	İ	Mlyauchl.in. or (Nitto adj Denko).as.) and	US-PGPUB;	
		((coat\$3 or deposit\$3 or (vacuum adj dry)	EPO; JPO;	
		or sputter\$3) with (silver or Ag or	DERWENT;	
		(transparent near2 conduct\$3)) with (rate near2 (deposit\$3)))	IBM_TDB	
4	82	(Nakamura.in. or Sasa.in. or Hieda.in. or	USPAT;	2004/01/12 00:40
	1	Miyauchi.in. or (Nitto adj Denko).as.) and	US-PGPUB;	2004/01/12 09:49
		((coat\$3 or deposit\$3 or (vacuum adj drv)	EPO; JPO;	
	1	or sputter\$3) with (silver or Ag)) and	DERWENT;	f
		((coat\$3 or deposit\$3 or (vacuum adj dry)	IBM_TDB	
		or sputter\$3) with (ITO or (indium near2	_	
	1	<pre>tin near2 oxide) or (high near2 (refract\$3 near2 index))))</pre>		
5	52	(Nakamura.in. or Sasa.in. or Hieda.in. or	USPAT;	0004/01/10 05 55
		Miyauchi.in. or (Nitto adj Denko).as.) and	US-PGPUB;	2004/01/12 09:21
		((coat\$3 or deposit\$3 or (vacuum adj drv)	EPO; JPO;	
		or sputter\$3) with (silver or Ag)) same	DERWENT;	
		((coat\$3 or deposit\$3 or (vacuum adj dry)	IBM TDB	ĺ
		or sputter\$3) with (ITO or (indium near2	-	
		<pre>tin near2 oxide) or (high near2 (refract\$3 near2 index))))</pre>	1	1
6	14	((Nakamura.in. or Sasa.in. or Hieda.in. or	HEDAM.	2004/01/12 22
		Miyauchi.in. or (Nitto adj Denko).as.) and	USPAT; US-PGPUB;	2004/01/12 09:19
	ļ į	((coat\$3 or deposit\$3 or (vacuum adj dry)	EPO; JPO;	
		or sputter\$3) with (silver or Aq)) and	DERWENT;	1
		((coat\$3 or deposit\$3 or (vacuum adj dry)	IBM TDB	
		or sputter\$3) with (ITO or (indium near2	_	1 1
		tin near2 oxide) or (high near2 (refract\$3	ł	0.
	ļ	near2 index))))) and (PDP or (plasma adj display))		
7	42	((Nakamura.in. or Sasa.in. or Hieda.in. or	USPAT;	2004/01/10 00 00
		Miyauchi.in. or (Nitto adj Denko).as.) and	US-PGPUB;	2004/01/12 09:22
		((coat\$3 or deposit\$3 or (vacuum adi dry)	EPO; JPO;]
		or sputter\$3) with (silver or Ag)) same	DERWENT;	1
	l í	((coat\$3 or deposit\$3 or (vacuum adi drv)	IBM_TDB	
		or sputter\$3) with (ITO or (indium near2		
]	tin near2 oxide) or (high near2 (refract\$3 near2 index))))) not (((Nakamura.in. or	1	
	İ	Sasa.in. or Hieda.in. or Miyauchi.in. or	1	
8		(Nitto adj Denko).as.) and ((coat\$3 or	1	
		deposits3 or (vacuum adj dry) or	i	
		sputter\$3) with (silver or Ag)) and		
	ļ	((coat\$3 or deposit\$3 or (vacuum adj drv)	1	
	į	or sputter\$3) with (ITO or (indium near2	1	
		tin near2 oxide) or (high near2 (refract\$3 near2 index))))) and (PDP or (plasma adj		
		display)))		ĺ
3	726	(427/108,109).CCLS.	USPAT;	2004/01/12 09:22
_	1		US-PGPUB	2004/01/12 09:22
9	1505	(427/124,125).CCLS.	USPAT;	2004/01/12 09:22
10	1050	/407/100 4 464 465 444	US-PGPUB	
.0	1956	(427/163.1,164,165,166).CCLS.	USPAT;	2004/01/12 09:23
L1	2418	(427/250,255.32,255.7).CCLs.	US-PGPUB	0001/01/10
	2.20	,,200,200.02,200.//.COLO.	USPAT;	2004/01/12 09:23
.2	2325	(427/404,419.1,419.2,419.3).CCLS.	US-PGPUB USPAT;	2004/01/12 09:23
_			US-PGPUB	
.3	686	(204/192.1,192.14).CCLS.	USPAT;	2004/01/12 09:23
		/204/102 15 102 25 102 25:	US-PGPUB	ł
4		(204/192.15,192.26,192.28).CCLS.	US-PGPUB USPAT; US-PGPUB	2004/01/12 09:24

C				
15	1103	(313/112,489).CCLS.	USPAT;	2004/01/12 09:24
16	0.050	1000 (000 000 000 000 000 000 000 000 00	US-PGPUB	
1.0	2352	(359/359,360,580,586,588,885,888).CCLS.	USPAT;	2004/01/12 09:24
17	12990	//427/100 1001 ggra	US-PGPUB	ĺ
- '	12990	((427/108,109).CCLS.) ((427/124,125).CCLS.)	USPAT;	2004/01/12 09:25
	!	((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.)	US-PGPUB	1
i		((427/250, 255.32, 255.7).CCLS.)		1
		((427/404, 419.1, 419.2, 419.3).CCLS.)		
J		((204/192.1,192.14).CCLS.)		1
	İ	((204/192.15,192.26,192.28).CCLs.)		1
		((313/112,489).CCLS.)	J	
ĺ		((359/359,360,580,586,588,885,888) CCTS)		
18	38	((204/192.15,192.26,192.28).CCLS.) and	USPAT;	2004/01/12 09:27
		(((313/112,489).CCLS.) or	US-PGPUB	2004/01/12 09:2/
		((359/359,360,580,586,588,885,888).CCLS.))		1
19	20	(((427/108,109).CCLS.)	USPAT:	2004/01/12 09:33
		((427/124,125).CCLS.)	US-PGPUB	
		((427/163.1,164,165,166).CCLS.)		1
1		((427/250, 255.32, 255.7).CCLs.)		
	i	((427/404,419.1,419.2,419.3).CCLS.)	ĺ	
1		((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.)		1
	}	((313/112,489).CCLS.)		
		((359/359,360,580,586,588,885,888).CCLs.))		f I
	ļ i	and ((sputter\$3 or (vacuum adj dry)) with		1
		(Ag or silver) with (temperature))		1
20	168	((sputter\$3 or (vacuum adi drv)) with (Ac	USPAT;	2004/01/12 09:33
		or silver) with (temperature))	US-PGPUB	2004/01/12 09.33
21	148	(((sputter\$3 or (vacuum adj dry)) with (Ag	USPAT;	2004/01/12 09:33
		or silver) with (temperature))) not	US-PGPUB	
]		((((427/108,109).CCLS.)		
		((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.)]
l		((427/250, 255.32, 255.7).CCLS.)		
1 1		((427/404,419.1,419.2,419.3).CCLS.)		
	ĺ	((204/192.1,192.14).CCLS.)		
		((204/192.15,192.26,192.28).CCLs.)		
1	- 1	((313/112,489),CCLS.)]
]		((359/359,360,580,586,588,885,888).CCLS.))		(!
1 !	ļ	and ((sputter\$3 or (vacuum adi drv)) with		1
1	. [(Ag or silver) with (temperature)))		
22	253	((coat\$3 or deposit\$3 or (vacuum adj dry)	USPAT;	2004/01/12 10:02
1	í	or sputter\$3) with (silver or Ag)) and	US-PGPUB;	
		((coat\$3 or deposit\$3 or (vacuum adj dry)	EPO; JPO;	f
	}	or sputter\$3) with (ITO or (indium near2	DERWENT;	1
]		tin near2 oxide) or (high near2 (refract\$3	IBM_TDB	
í l		near2 index)))) and (((427/108,109).CCLS.) ((427/124,125).CCLS.)		1
	- 1	((427/163.1,164,165,166).CCLS.)		ĺ
		((427/250,255.32,255.7).CCLS.)		[
	1	((427/404,419.1,419.2,419.3).CCLS.)		
i l		((204/192.1,192.14).CCLS.)		
	- 1	((204/192.15,192.26,192.28).CCLS.)		l l
		((313/112,489).CCLS.)		
L		((359/359,360,580,586,588,885,888).CCLS.))		'

23	7			
23	248		USPAT;	2004/01/12 09:50
		or sputter\$3) with (silver or Ag)) and	US-PGPUB;	1
	ĺ	((coat\$3 or deposit\$3 or (vacuum adj dry)	EPO; JPO;	
		or sputter\$3) with (ITO or (indium near2	DERWENT;	1
-)		tin near2 oxide) or (high near2 (refract\$3	IBM_TDB	
		near2 index)))) and (((427/108,109),CCLS.)	_	1
		((427/124,125).CCLS.)		Í
		((427/163.1,164,165,166).CCLS.)		
		((427/250,255.32,255.7).CCLS.)		ļ
	ļ	((427/404,419.1,419.2,419.3).CCLS.)	1	
		((204/192.1,192.14).CCLS.)		
		((204/192.15,192.26,192.28).CCLS.)	1	ł
	i	((313/112,489).CCLS.)		
		((359/359,360,580,586,588,885,888).CCLS.)))	1	
	ĺ	not ((Nakamura.in. or Sasa.in. or		
		Hieda.in. or Miyauchi.in. or (Nitto adj		
		Don'to and the different or (Nitto adj		1
		Denko).as.) and ((coat\$3 or deposit\$3 or		
		(vacuum adj dry) or sputter\$3) with		
	İ	(silver or Ag)) same ((coat\$3 or deposit\$3	i	1
		or (vacuum adj dry) or sputter\$3) with		
	1	/ (ITO or (indium near) tin near? ovide) or	I	
24	1	(high near2 (refract\$3 near2 index))))	1	
4	30	(((Coat\$3 or deposit\$3 or (vacuum adi	USPAT;	2004/01/12 09:51
		dry) or sputter\$3) with (silver or Ag))	US-PGPUB;	-001/01/12 09:51
		and ((coat\$3 or deposit\$3 or (vacuum adi	EPO; JPO;	
	i	(dry) or sputter\$3) with (TTO or (indiam	DERWENT;	
		near2 tin near2 oxide) or (high near2	IBM TDB	
		(refract\$3 near2 index)))) and	100-100	1
		(((427/108,109).CCLS.)		
		((427/124,125).CCLS.)		
	i	((427/163.1,164,165,166).CCLS.)		1
		((427/250,255.32,255.7).CCLS.)		
	i	((427/404,419.1,419.2,419.3).CCLS.)		1
		((204/192 1 102 14) gorg		
	1	((204/192.1,192.14).CCLS.)		
		((204/192.15,192.26,192.28).CCLS.)		ĺ
]	((313/112,489).CCLS.)		
	1	((359/359,360,580,586,588,885,888).CCLS.)))		1
		not ((Nakamura.in. or Sasa.in. or		
		Hieda.in. or Miyauchi.in. or (Nitto adj		1
		Denko).as.) and ((coat\$3 or deposit\$3 or		ĺ
	1 .	(Vacuum ad] dry) or sputter\$3) with		
		(silver or Ag)) same ((coat\$3 or deposit\$3)		
]	or (vacuum adi drv) or sputters3) with		
	[(ITO or (indium near2 tin near2 oxide) or		
_	[(filgh hear2 (refract\$3 hear2 index)\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\		
5	102	4ndcdBD\$3oor(pepematadjodispasyum adj dry)	USPAT;	0004/01/10 05
		or sputter\$3) with (silver or Ag) \ and		2004/01/12 09:58
		((coat\$3 or deposit\$3 or (vacuum adj dry)	US-PGPUB;	
		or sputter\$3) with (ITO or (indium near2	EPO; JPO;	
]	tin near? ovide) or (high mana)	DERWENT;	
		tin near2 oxide) or (high near2 (refract\$3	IBM_TDB	
		near2 index)))) and (((427/108,109).CCLS.)		
]	((427/124,125).CCLS.)		
i				
		((427/163.1,164,165,166).CCLS.)		
		((427/250,255.32,255.7).CCLS.)		
		((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.)		
		((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.)		I
		((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.)		
		((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.)		
		((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.)))		
		((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.)		

26	154		USPAT;	2004/01/12 09:59
		or sputter\$3) with (silver or Ag)) and	US-PGPUB;	ĺ
		((coat\$3 or deposit\$3 or (vacuum adj dry)	EPO; JPO;	
i		Of Sputters) With (ITO or (indium near)	DERWENT;	1
		tin near2 oxide) or (high near2 (refracts3 near2 index)))) and (((427/108,109).CCLS.)	IBM_TDB	
1	1	near2 index)))) and (((427/108,109).CCLS.)	, –]
		((427/124,125).CCLS.)		İ
!	1	((427/163.1,164,165,166).CCLS.)		
ĺ		((427/250,255.32,255.7).CCLS.)	ĺ	ĺ
	1	((427/404, 419.1, 419.2, 419.3).CCLS.)		
ĺ		((204/192.1,192.14).CCLs.)	İ	
		((204/192.15,192.26,192.28).CCLS.)		
		((313/112,489).CCLS.)	1	
		((359/359,360,580,586,588,885,888).CCLS.)))		
		and ((sputter\$3 or deposit\$3 or coat\$3)		
27	135	with temperature)	i	1
1 2 1	133		USPAT;	2004/01/12 09:58
		dry) or sputter\$3) with (silver or Aq))	US-PGPUB;	1 12, 22 33,00
		and ((coats) or deposits) or (vacuum adi	EPO; JPO;	
		dry or sputter\$3) with (ITO or (indium	DERWENT;	
		near2 tin near2 oxide) or (high near2	IBM TDB	1
		(refract\$3 near2 index)))) and		
		(((427/108,109).CCLS.)	1	1
	1	((427/124,125).CCLS.)		
	1	((427/163.1,164,165,166).CCLS.)	1	
		((427/250,255.32,255.7).CCLS.)		
		((427/404,419.1,419.2,419.3).CCLS.)		
	1	((204/192.1,192.14).CCLS.)	ĺ	
		((204/192.15,192.26,192.28).CCLS.)		ļ
	1	((313/112,489).CCLS.)	1	
		((359/359,360,580,586,588,885,888).CCLS.)))		
		and (Sputter\$3 or deposit\$3 or coat\$3)		
		With temperature)) not ((((coats3 or		
		deposits3 or (vacuum adi drv) or		1
		Sputter\$3) with (silver or Ad)) and	ĺ	
		((Coat)) or deposit() or (vacuum adi drv)	ī	1
		Of Sputter(3) With (ITO or (indium near)		1
		Lin near2 Oxide) or (high near2 (refreeter		
		near2 index))) and (((427/108,109).CCLS.)		
		((42//124,125),CCLS.)		
	1	((427/163.1,164,165,166).CCLS.)		1
		[((42//250,255,32,255.7),CCLS.)		
		! ((42//404,419.1,419.2,419.3).CCLS.)		ļ
		((204/192.1,192.14),CCLS.)		
		((204/192.15,192.26,192.28).CCLS.)		1 1
	ĺ	[((313/112,489).CCLS.)		į l
		((359/359,360,580,586,588,885,888).CCLS.)))		
	1	NOT ((Nakamura.in, or Sasa.in, or		}
		Hieda.in. or Miyauchi.in. or (Nitto adi		
	1	Denko).as.) and ((coat\$3 or deposit\$3 or		1
		(vacuum ad] dry) or sputter\$3) with		
		(Silver or Ag)) same ((coat\$3 or deposit\$3		
		or (vacuum ad) dry) or sputter\$3) with		
	1	(110 or (indium near2 tin near2 oxide) or		
20	,_	(High Redra (Terracts) near2 index))))))		į l
28	47	4144 (¢BBES6rofpdapmaia63 dispyanyhh adi	USPAT;	2004/01/12 09:59
		dry, or sputter\$3) with (silver or Aq))	US-PGPUB	2001/01/12 03:59
		and ((coats) or deposits or (vacuum adi		1
		dry) or sputter\$3) with (ITO or (indium		
		near2 tin near2 oxide) or (high near2		
		(refract)3 near2 index()))) and		[
	[]	(((427/108,109).CCLS.)		
		((427/124,125).CCLS.)		
	[]	((427/163.1,164,165,166).CCLS.)]
		((427/250,255.32,255.7).CCLS.)		İ
		((427/404,419.1,419.2,419.3).CCLS.)		
		((204/192.1,192.14).CCLS.)		
		((204/192.15,192.26,192.28).CCLS.)		
		((313/112,489).CCLS.)		0
		((359/359,360,580,586,588,885,888).CCLS.)))		
		and ((sputter\$3 or deposit\$3 or coat\$3)	ļ	1
	L	with temperature)) and (sputter\$3 with		
	troses 1/2	temperature)		

29	186	<pre>(((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same</pre>	USPAT;	2004/01/12 10:10
		((coat\$3 or deposit\$3 or (vacuum adj dry)	US-PGPUB	
		or sputter\$3) With (ITO or (indium near2		
		tin near2 oxide) or (high near2 (refract\$3		
	İ	[nearz index)])) same (repeats3 or		
		multilayer or (multi adj layer) or	}	
]	1	(multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))		
30	27	((((coat\$3 or deposit\$3 or (vacuum adj	USPAT;	2004/01/10 10 05
		dry) or sputter\$3) with (silver or Ag))	US-PGPUB	2004/01/12 10:06
		same ((coat\$3 or deposit\$3 or (vacuum adi	00 10105	1
		drv) or sputter\$3) with (TTO or (indium	1	
	i	near2 tin near2 oxide) or (high near2		
		<pre>(refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or</pre>		i
		(multiple adj layer) or (PDP) or (plasma	1	
		adj display) or filter or stack))) and		ļ
		(((427/108,109).CCLS.)	ĺ	
		((427/124,125).CCLS.)		
		((427/163.1,164,165,166).CCLS.)	ļ	
1	1	((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.)		
		((204/192.1,192.14).CCLS.)		
		((204/192.15,192.26,192.28).CCLs.)	İ	
		((313/112,489).CCLS.)		
31		((359/359,360,580,586,588,885,888).CCLS.))		
. 31	14		USPAT;	2004/01/12 10:19
		dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj	US-PGPUB	Í
İ		dry) or sputter\$3) with (ITO or (indium		
		near2 tin near2 oxide) or (high near2]	
		(refract\$3 near2 index)))) same (repeat\$3	ĺ	
		or multilayer or (multi adj layer) or		
ļ		(Muitiple ad] layer) or (PDP) or (plasma	1	
		adj display) or filter or stack))) and		
		((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)	ļ	
32	1844	(((coat\$3 or deposit\$3 or (vacuum adi drv)	USPAT;	2004/01/12 10:14
		or sputter\$3) with (silver or Aq)) same	US-PGPUB	2004/01/12 10:14
i		((Coats) or deposit\$3 or (vacuum adi drv)		
		or sputter\$3) with (ITO or (indium near2		
ĺ		tin near2 oxide) or (high near2 (refract\$3 near2 index)))))		
33	134	((((coat\$3 or deposit\$3 or (vacuum adj	USPAT;	2004/01/10 10 10
		dry) or sputter\$3) with (silver or Ag))	US-PGPUB	2004/01/12 10:10
		same ((coat\$3 or deposit\$3 or (vacuum adi		
	ĺ	QTV Or Sputter\$3) with (TTO or (indium		ļ
		near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))) and		
	İ	((sputter\$3 or (vacuum adj (dry or		ļ į
		deposit\$3)) or PVD) with temperature)		
34	120	(((((coat\$3 or deposit\$3 or (vacuum adi	USPAT;	2004/01/12 10:10
		ary) or sputter\$3) with (silver or Ag))	US-PGPUB	
		same ((coat\$3 or deposit\$3 or (vacuum adj		
		dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2		i
	!	(refract\$3 near2 index)))))) and		
		((sputter\$3 or (vacuum adj (dry or		
	ļ i	deposit\$3)) or PVD) with temperature)) not		
	j j	(((((coat\$3 or deposit\$3 or (vacuum adi		
	ļ	dry) or sputter\$3) with (silver or Ag))		
j	į į	same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium		
	! [near2 tin near2 oxide) or (high near2		
i		(refract\$3 near2 index)))) same (repeat\$3		
		or multilayer or (multi adj laver) or		
ĺ		(multiple adj laver) or (PDP) or (plasma		
		adj display) or filter or stack))) and		
ĺ		((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))		

35	386	(((coat\$3 or deposit\$3 or (vacuum adj dry)	USPAT;	2004/01/12 10:1
	!	or sputter\$3 or PVD) with (silver or Ag))	US-PGPUB	
		and ((coat\$3 or deposit\$3 or (vacuum adj		J
		dry) or sputter\$3 or PVD) with ((high		
36		near2 (refract\$3 near2 index))))))		
36	114		USPAT;	2004/01/12 10:1:
	!	dry) or sputter\$3 or PVD) with (silver or	US-PGPUB	
	ĺ	Ag)) and ((coat\$3 or deposit\$3 or (vacuum	Í	
		adj dry) or sputter\$3 or PVD) with ((high		1
		near2 (refract\$3 near2 index)))))) and		
		(((427/108,109).CCLS.) ((427/124,125).CCLS.)		1
		((427/163.1,164,165,166).CCLS.)		Í
		((427/250,255.32,255.7).CCLS.)	1	
		((427/404,419.1,419.2,419.3).CCLS.)		1
		((204/192.1,192.14).CCLS.)		
		((204/192.15,192.26,192.28).CCLS.)		
		((313/112,489).CCLS.)		í
		((359/359,360,580,586,588,885,888).CCLS.))		

37	103	(((((coat\$3 or deposit\$3 or (vacuum adj	USPAT;	2004/01/12 10:15
		dry) or sputter\$3 or PVD) with (silver or	US-PGPUB	1
		Ag)) and ((coat\$3 or deposit\$3 or (vacuum		
		adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index)))))) and		
		(((427/108,109).CCLS.)	1	
		((427/124,125).CCLS.)		
Ĭ		((427/163.1,164,165,166).CCLS.)		İ
	1.	((427/250,255.32,255.7).CCLs.)		
1		((427/404,419.1,419.2,419.3).CCLS.)		
		((204/192.1,192.14).CCLS.)	ĺ	1
		((204/192.15,192.26,192.28).CCLS.)		
		((313/112,489).CCLS.)		
		((359/359,360,580,586,588,885,888).CCLS.)))		
		not (((((((coat\$3 or deposit\$3 or (vacuum		
		adj dry) or sputter\$3) with (silver or	ĺ	
	1	Ag)) same ((coat\$3 or deposit\$3 or (vacuum		
		adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high		
		near2 (refract\$3 near2 index)))))) and	!	
	1	((sputter\$3 or (vacuum adj (dry or		
		deposit\$3)) or PVD) with temperature)) not		
		(((((coat\$3 or deposit\$3 or (vacuum adi		
i		dry) or sputter\$3) with (silver or Ag))		- 50
		same ((coat\$3 or deposit\$3 or (vacuum adj	İ	
		dry) or sputter\$3) with (ITO or (indium		1
		near2 tin near2 oxide) or (high near2		
		(refract\$3 near2 index)))) same (repeat\$3		
		or multilayer or (multi adj layer) or		
		(multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and		
]		((sputter\$3 or (vacuum adj (dry or		
1		deposit\$3)) or PVD) with temperature))) or		
		(((((coat\$3 or deposit\$3 or (vacuum adj		
	1	dry) or sputter\$3) with (silver or Ag))		!
		same ((coat\$3 or deposit\$3 or (vacuum adj		i
		dry) or sputter\$3) with (ITO or (indium		
		near2 tin near2 oxide) or (high near2		1
	1 1	(refract\$3 near2 index)))) same (repeat\$3		
		or multilayer or (multi adj layer) or		
İ		(multiple adj layer) or (PDP) or (plasma		
	!!!	adj display) or filter or stack))) and		
		(((427/108,109).CCLS.) ((427/124,125).CCLS.)		l
		((427/163.1,164,165,166).CCLS.)		ł I
		((427/250,255.32,255.7).CCLS.)		
		((427/404,419.1,419.2,419.3).CCLS.)		
		((204/192.1,192.14).CCLS.)		
1		((204/192.15,192.26,192.28).CCLS.)		1
		((313/112,489).CCLS.)		
		((359/359,360,580,586,588,885,888).CCLS.)))		
		or (((((coat\$3 or deposit\$3 or (vacuum adj		
		dry) or sputter\$3) with (silver or Ag))		
1		same ((coat\$3 or deposit\$3 or (vacuum adj		
] :		dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2		_ 1
		(refract\$3 near2 index)))) same (repeat\$3		
		or multilayer or (multi adj layer) or		
	ļ	(multiple adj layer) or (PDP) or (plasma		
		adj display) or filter or stack))) and		
	ĺ	((sputter\$3 or (vacuum adj (dry or		
		deposit\$3)) or PVD) with temperature)))		
38	33	((((coat\$3 or deposit\$3 or (vacuum adj	USPAT;	2004/01/12 10:21
		dry) or sputter\$3 or PVD) with (silver or	US-PGPUB	
		Ag)) and ((coat\$3 or deposit\$3 or (vacuum	i	
	1	adj dry) or sputter\$3 or PVD) with ((high pear2 (refract\$3 pear2 index))))) and		
	1	near2 (refract\$3 near2 index)))))) and ((sputter\$3 or (vacuum adj (dry or		
!]		deposit\$3)) or PVD) with temperature)		

39	T				
39	30		USPAT;	2004/01/12 10:1	~
		Qry/ Or Sputters3 or PVD) with (gilwor or	US-PGPUB	2001/01/12 10:1	۶ ا
		(coats3 or deposits3 or /wacuum	10100		-
		auj dry) or sputter\$3 or PVD) with //high		1	i
		nearz (refract\$3 near2 index)))))) and			
		((Sputter\$3 or (Vacuum adi (dry or	Í	1	ı
		(deposit§3)) or PVD) with temperature() not	1		J
		((((COat\$3 or deposits3 or (vacuum adi	1	1	Ì
		dry) or sputter\$3) with (silver or Ag))	1		- }
		same ((coat\$3 or deposit\$3 or (vacuum adj		i	
		dry) or sputter\$3) with (ITO or (indium	1		- {
	1	near2 tin near2 oxide) or (high near2	-	Ì	
		(refract\$3 near2 index)))) same (repeat\$3			
	1	or multilayer or (multi adj layer) or		1	
		(multiple adj layer) or (PDP) or (plasma	}		ļ
	i	adj display) or filter or stack))) and		i	
		((sputter\$3 or (vacuum adj (dry or	1		- {
	ĺ	deposit\$311 or pup)		1	
40	291	deposit\$3)) or PVD) with temperature))	ĺ	1	- [
	232		EPO; JPO;	2004/01/12 10:25	,
	ļ	deposit\$3)) or PVD) with temperature) and (Ag or silver)	DERWENT;]	1
41	. 92	(Ag of Silver)	IBM TDB		
	. 22	((sputter\$3 or (vacuum adj (dry or	EPO; JPO;	2004/01/12 10:21	1
		deposit\$3)) or PVD) with temperature) with	DERWENT;	,,	
42	22	(Ag or silver)	IBM TDB		1
12	22	(((sputter\$3 or (vacuum adj (dry or	EPO; JPO;	2004/01/12 10:26	
		deposit(\$3)) or PVD) with temperature) and	DERWENT;	,, 12 10.20	Ì
		(Ag or silver)) and (multilayer or (multi	IBM TDB		1
i		adj layer) or stack or filter or PDP or			
		(plasma adj display))			ļ